

Mail Stop: After Final

PATENT
8007-1118

IN THE U.S. PATENT AND TRADEMARK OFFICE

In re application of

Masaru HOSOKAWA et al.

Conf. 4713

Application No. 10/594,567

Group 1793

Filed September 27, 2006

Examiner S. Abu Ali

MATERIAL FOR CHEMICAL VAPOR DEPOSITION
AND THIN FILM FORMING METHOD

AMENDMENT AFTER FINAL REJECTION

Assistant Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

June 12, 2009

Sir:

In response to the Official Action mailed March 12, 2009, please amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks begin on page 6 of this paper.